



00684.002535.3

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Q. T. Le
Yuichi YAMADA et al.)	
	:	Group Art Unit: 2878
Application No.: 10/024,139)	
	:	Confirmation No.: 4039
Filed: December 21, 2001)	
	:	
For: SCANNING EXPOSURE APPARATUS AND)	:	
DEVICE MANUFACTURING METHOD	:	May 16, 2005

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Further to the Information Disclosure Statement filed December 21, 2001, in compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. The documents were cited by the Japanese Patent Office in connection with Applicants' corresponding Japanese application. Copies of the Japanese patent documents are also enclosed, along with an excerpt translation of the Japanese Office Action.

Japanese patent document number 4-354320 relates to a detecting device that irradiates a wafer 2 with a plurality of pinhole images. Incidence position information of pinhole images are made incident on a detecting plane 17, and inputted height information is sent from a focus controller 18 to stage controller 4.

Japanese patent document number 7-113613 relates to an imaging sensor capable of high speed scanning. An area sensor 8 combines an electronic shutter and photoelectric elements for controlling charge accumulation at a unit of a picture element and outputs the charge that is accumulated through light beam scanning.

Japanese patent document 8-162394 relates to an aligning operation whereby a first wafer is subjected to an aligning process, and second and subsequent wafers are subjected to an alignment process that includes an offset component.

Applicants request that the cited information be considered by the Examiner and that a copy of the enclosed PTO-1449 Form be initialed and returned indicating that such information has been considered.

No fee is believed to be due with the filing of this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed necessary for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Scott D. Malpede
Registration No. 32,533

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

SDM/eab



FORM PTO 1449 (modified)				ATTY DOCKET NO. 00684.002535.3		APPLICATION NO. 10/024,139	
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE				APPLICANT Yuichi YAMADA et al.			
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				FILING DATE December 21, 2001		GROUP 2878	
Filed: May 16, 2005							
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US-5,118,957	06/02/1992	Kawashima et al.	250	561	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		4-345320	12/08/1992	Japan			Abstract
		7-113613	05/02/1995	Japan			Abstract
		8-162394	06/21/1996	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER				DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.